

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings of claims in the application:

Listing of Claims:

1. (Currently amended): A method for manufacturing a semiconductor power device, comprising:
 - identifying an active region on a semiconductor die;
 - identifying a first region in said active region;
 - identifying a second region in said active region;
 - identifying a third region in said active region;
 - providing a first cell design by which active cells in said first region will be fabricated; ~~and~~
 - providing a second cell design by which active cells in said second region will be fabricated[.]; and
 - providing a third cell design by which active cells in said third region will be fabricated,
 - wherein first active cells fabricated according to said first cell design being are
 - different from second active cells fabricated according to said second cell design[.],
 - wherein third active cells fabricated according to said third cell design are
 - different from said first active cells and from said second active cells.
2. (Original): The method of claim 1 wherein said first cell design and said second cell design include cell dimensions such that a cell density of said first region is different from that of said second region.
3. (Original): The method of claim 1 wherein said first cell design includes at least one physical dimension different from that included in said second cell design.

4. (Original): The method of claim 3 wherein said physical dimension includes a channel width.

5. (Original): The method of claim 4 wherein said physical dimension includes a cell die area.

6. (Original): The method of claim 1 wherein said first cell design includes a material composition for cells that is different from that of said second cell design.

7. (Original): The method of claim 1 wherein said first cell design differs from said second cell design with respect to current density.

8. (Original): The method of claim 1 wherein said first cell design differs from said second cell design with respect to source resistance.

9. (Original): The method of claim 1 wherein said first cell design differs from said second cell design with respect to transconductance.

10. (Original): The method of claim 1 wherein said first cell design differs from said second cell design with respect to gain.

11. (Original): The method of claim 1 wherein said first cell design differs from said second cell design with respect to threshold voltage.

12. (Original): The method of claim 1 wherein said first cell design and said second cell design are field effect transistors.

13. (Original): The method of claim 1 wherein said first cell design and said second cell design are memory cells.

14. (New): A semiconductor power device fabricated in accordance with the method of claim 1.